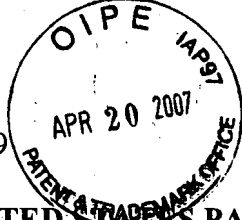


Docket No.: 060188-0839



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of	:	Customer Number: 53080
Akio MISAKA	:	Confirmation Number: 6593
Application No.: 10/824,529	:	Group Art Unit: 1756
Filed: April 15, 2004	:	Examiner: ROSASCO, STEPHEN D

For: PHOTOMASK, PATTERN FORMATION METHOD USING PHOTOMASK AND MASK DATA CREATION METHOD FOR PHOTOMASK

RESPONSE TO RESTRICTION REQUIREMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Noting the Office Action of March 23, 2007 wherein restriction has been required, Applicant hereby elects Group I (claims 1-38, drawn to a mask and a method of using) for prosecution in the above-identified application.

To the extent necessary, a petition for an extension of time under 37 C.F.R. 1.136 is hereby made. Please charge any shortage in fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account 500417 and please credit any excess fees to such deposit account.

Respectfully submitted,

McDERMOTT WILL & EMERY LLP

Michael E. Fogarty
Registration No. 36,139

Please recognize our Customer No. 53080
as our correspondence address.

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Date: April 20, 2007

WDC99 1379028-1.060188.0839